

Performance Study of Silicon Photomultipliers as Photon Detectors for PET

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Motivation

Positron Emission Tomography (PET) is a non-invasive method for indepth and in-vivo imaging of tissue. The annihilation gamma-rays of 511 keV, originating from a positron-electron annihilation, are usually detected indirectly, through scintillation in inorganic crystals. Photon detectors, like Photomultiplier Tubes (PMTs), detect the scintillation light. The majority of PET devices use PMTs, but due to their size, relatively poor ratio of active to total surface and high price, which is a significant fraction of the total cost of the device, it is worthwhile to search for alternate detectors of visible and infrared photons. The sensitivity of PMTs to magnetic fields and the increasing requirement to unify different image modalities in one measurement, provides an additional reason to search for new detectors. One would like to incorporate a PET apparatus inside a MRI magnet for simultaneous imaging of tissue function and density. A new type of semiconductor detector, the Silicon Photomultiplier (SiPM) looks very promising. Surface sensitivity, energy resolution and timing resolution have been measured for several different samples and types.

Energy Resolution

Performance of several SiPMs have been measured by coupling a LYSO crystal to the SiPMs and measuring the coincidence annihilation γ 's from ²²Na source.

PET Setup: Single SiPM



Typical SiPM Characteristics:

- Low operating voltage ~ 10 100 V
- High gain ~ 10⁵ 10⁶
- Peak PDE up to 65% (@400nm) PDE = QE x ε_{geig} x ε_{geo}

$$\epsilon_{geo} \sim microcell fill factor$$

- Good time resolution ~ 100-200 ps
- Insensitive to magnetic fields
- High dark counts ~several 100kHz/mm²



Surface Sensitivity

Surface sensitivity is assessed by exposing each SiPM to a pulsed laser beam. The SiPM is placed in the focal plane of the laser beam ($\sigma \approx 5\mu$ m). To produce 2D scans the SiPM is moved relative to the light source to measure of the count rate of single photons hits over the surface of the silicon photomultiplier. Selection was done on single pixel pulse height in a ~ 10 ns TDC time window.



Response of the Silicon Photomultiplier to low light intensity pulses (single photon level) from a PILAS laser. Without a scintillator attached – pure SiPM. SiPM's with larger pixels have better timing properties.



Hamamatsu MPPCs H100C



STMicroelectronics



The SiPM of STMicroelectronics (STM) has special trenches between the pixels filled with a metal oxide which aims to reduce electrooptical crosstalk between neighbouring pixels. This results in a smaller fill factor (~36%) compared to the others.

1 µm step size

Hamamatsu (H050C, H100C) vs. Photonique (S137) vs. Pulsar/MEPH (E407)

